

IN THE CLAIMS:

Kindly cancel ~~claims~~ 134-136 without prejudice or disclaimer.

Kindly amend claims 137 and 144 as follows:

--<sup>1</sup>~~137~~. (Amended) A method of preparing an electron-emitting device, comprising the steps of:

*g1*  
forming electrodes opposed to each other on a substrate;

forming between the electrodes <sup>and in contact therewith</sup> an insulating layer in which fine particles are completely enclosed; and

etching the insulating layer so as to partially expose the fine particles.

[introducing fine particles into an insulating layer, said fine particles being enclosed in the insulating layer so as to partially expose said fine particles.]--

--<sup>2</sup>~~144~~. (Amended) A method of preparing an electron-emitting device comprising the steps of:

*g2*  
forming electrodes opposed to each other on a substrate;

forming between the electrodes <sup>and in contact therewith</sup> a semiconductor layer in which fine particles are completely enclosed; and

etching the semiconductor layer so as to partially expose the fine particles.